

INFORMATION DISCLOSURE CITATION IN AN APPLICATION						ATTY. DOCKET NO. 60188-653		SERIAL NO. 10/661,540			
(PTO-1449)						APPLICANT Masayuki ENDO, et al.					
						FILING DATE September 15, 2003		GROUP 1756			
U.S. PATENT DOCUMENTS											
EXAMINER'S INITIALS		CITE NO.	Document Number Number-Kind Code ² (if known)		Publication Date MM-DD-YYYY		Name of Patentee or Applicant of Cited Document		Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
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FOREIGN PATENT DOCUMENTS											
EXAMINER'S INITIALS		CITE NO.	Foreign Patent Document Country Code ³ -Number ⁴ -Kind Codes (if known)		Publication Date MM-DD-YYYY		Name of Patentee or Applicant of Cited Document		Pages, Columns, Lines Where Relevant Figures Appear	Translation	
										Yes	No
KAD		A	JP P2001-316863		11/16/2001		TDK CORP		Class/sub	(Japan w/English Abstract)	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)											
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KAD			M. Switkes et al., "Immersion lithography at 157 nm", J. Vac. Sci. Technolo., B19, 2353 (2001)								
EXAMINER V. Tuda						DATE CONSIDERED 11-21-05					

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